

PATENTS

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Haruo SUNAKAWA, et al. **Examiner:** Unassigned
Serial No: Unassigned **Art Unit:** Unassigned
Filed: Herewith **Docket:** 14463

JC986 U.S. PTO
09/821411
03/29/01

For: METHOD OF MANUFACTURING A NITROGEN-BASED
SEMICONDUCTOR SUBSTRATE AND A SEMICONDUCTOR ELEMENT
BY USING THE SAME

Dated: March 29, 2001

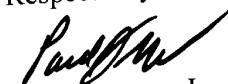
Assistant Commissioner for Patents
United States Patent and Trademark Office
Washington, D.C. 20231

CLAIM OF PRIORITY

Sir:

Applicants in the above-identified application hereby claim the right of priority
in connection with Title 35 U.S.C. § 119 and in support thereof, will submit in due course a
certified copy of Japanese Patent Application No. 91963/2000, filed on March 29, 2000.

Respectfully submitted,


Paul J. Esatto, Jr.

Registration No.: 30,749

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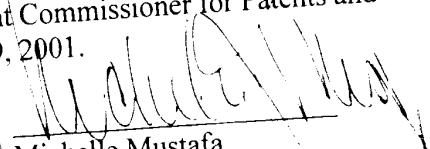
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Dated: March 29, 2001


Michelle Mustafa

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